Sheet 1 of 1

INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)					Atty. Docket No. P29771		Application No. 10/576,023	
					Applicant Kimiaki TOSHIKIYO			
						I.A. Filing Date December 15, 2004		Group 2622
			U	S. PATENT DOC				
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	2	Toshikiyo et al., "A K, 02/14/2007.	MOS Image Sens	or with Microlenses B	ailt by Sub-Wave	elength Patterning	g", 2007 IEEE ISSC	C session 28.8
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